

Appln. No. 10/621,497
Response dated February 15, 2006
Reply to Office Action dated December 7, 2005

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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1765



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuhiro Iwai, et al.
Appln. No. : 10/621,497
Filed : July 17, 2003
Title : PLASMA PROCESSING APPARATUS AND PLASMA
PROCESSING METHOD

OK to enter

Conf. No. : 2610
TC/A.U. : 1765
Examiner : Lan Vinh

LV

3/2/06

Customer No. : 000,116
Docket No. : 35908

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

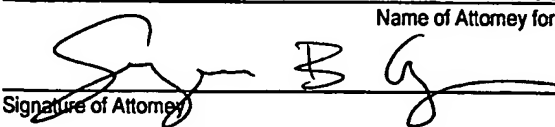
RESPONSE "C"
AFTER FINAL UNDER RULE 1.116

Sir:

This communication is filed in response to the Office Action dated December 7, 2005
(Paper No. 120105). The three-month period for responding to the Office Action expires on
March 7, 2006.

The following remarks are made for the Examiner's consideration.

Remarks/Arguments begin on page 2 of this paper.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below.	
Suzanne B. Gagnon	
Name of Attorney for Applicant(s)	
	February 15, 2006
Signature of Attorney	Date